

3D detector design

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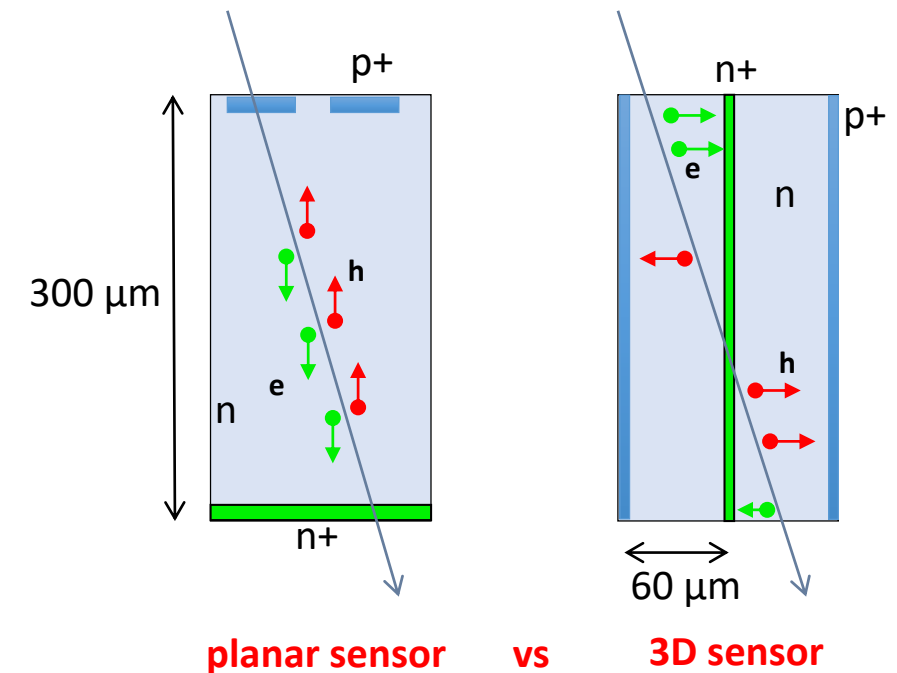
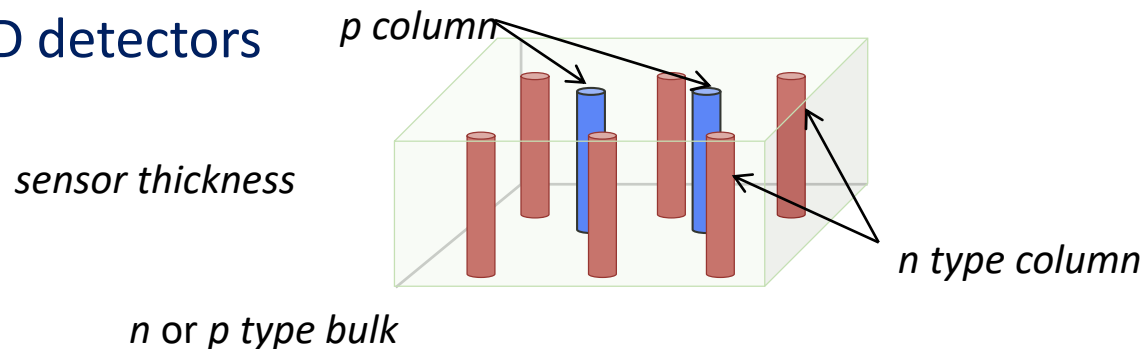
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Introduction

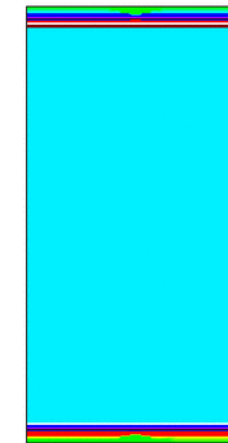
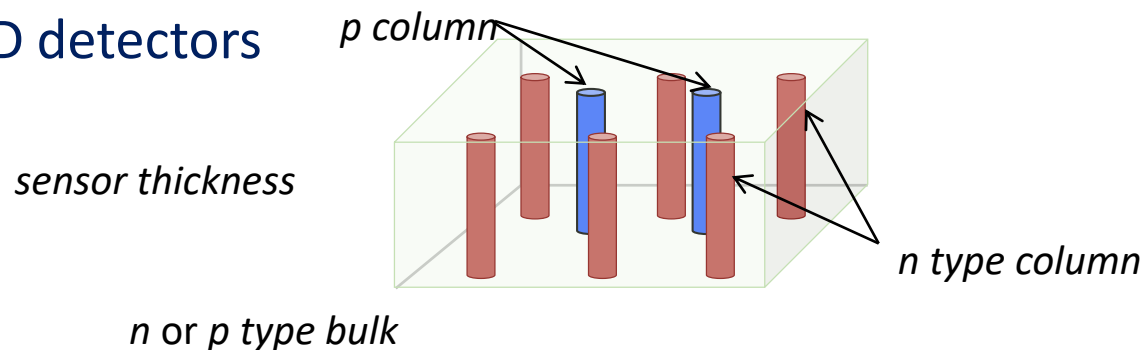
Pixel with good timing properties (1)

- What we were looking for:
 - Detector with fast charge collection (less than 500 ps)
 - Characteristic output signal shape independent from the particle track inside the silicon medium
- How can it be achieved?
 - Fast charge collection:
 - Using a detector technology which is capable of collecting electrons and holes in the requested time interval
- Chosen technology:
 - Silicon 3D detectors



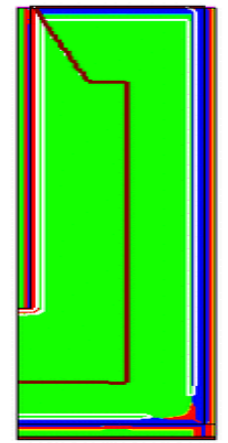
Pixel with good timing properties (1)

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planar sensor

vs

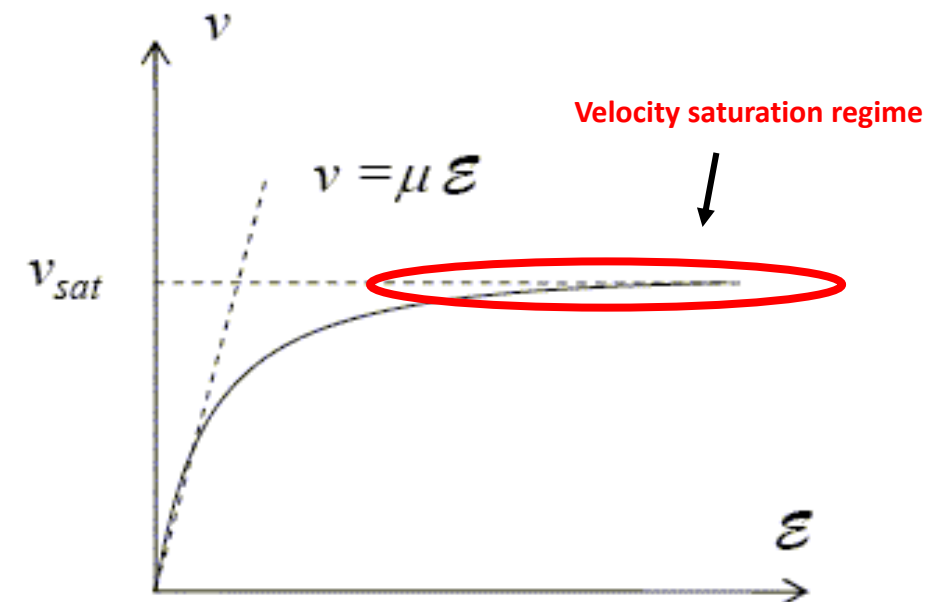


3D sensor

Pixel with good timing properties (2)

- How can it be achieved?
 - Signal output:
 - Following **Ramo theorem**, which describes the induced current on a electrode of a detector by a crossing particle, we need a detector with a possible constant electric field and charge velocity over the entire pixel volume.
 - v = charge velocity
 - E_w = Weighting field
 - Velocity can be hold mostly constant, if detector operates at velocity saturation.
 - Electric field must be over 10 kV/cm
 - Constant electric field is more challenging:
 - Need to work on the pixel geometry:
 - Form of the pixel and electrodes
 - Electrode position inside the pixel

$$i_1 = q_m \nabla \left(\frac{V_m}{V_1} \right) \cdot \mathbf{v} = -q_m \mathbf{E}_w \cdot \mathbf{v}$$



Work organization

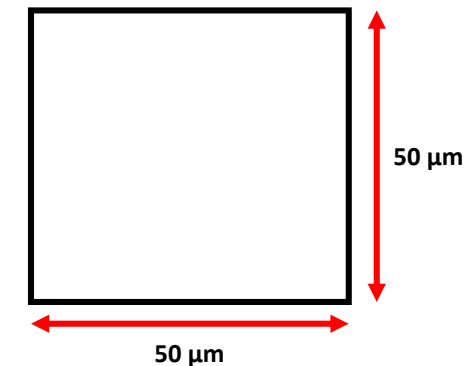
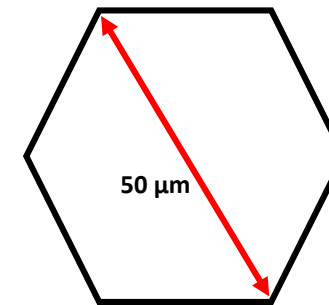
- Starting with 2D design of pixel cross-sections
 - Useful to understand carrier velocity and electric field between the electrodes
 - Less computational resources are needed
 - 2D models are defined with less than 50k points/meshes (3D models reaches easily more than 500k)
 - More geometric solutions can be explored in less time
- Selection of the geometries with the best properties
 - Evaluation of Electric field over the entire area (presence of possible low field areas)
 - Detector must operate at velocity saturation
- 3D design
 - Repeating detector design, including more structural details and repeat velocity and electric field analysis.

2D model design

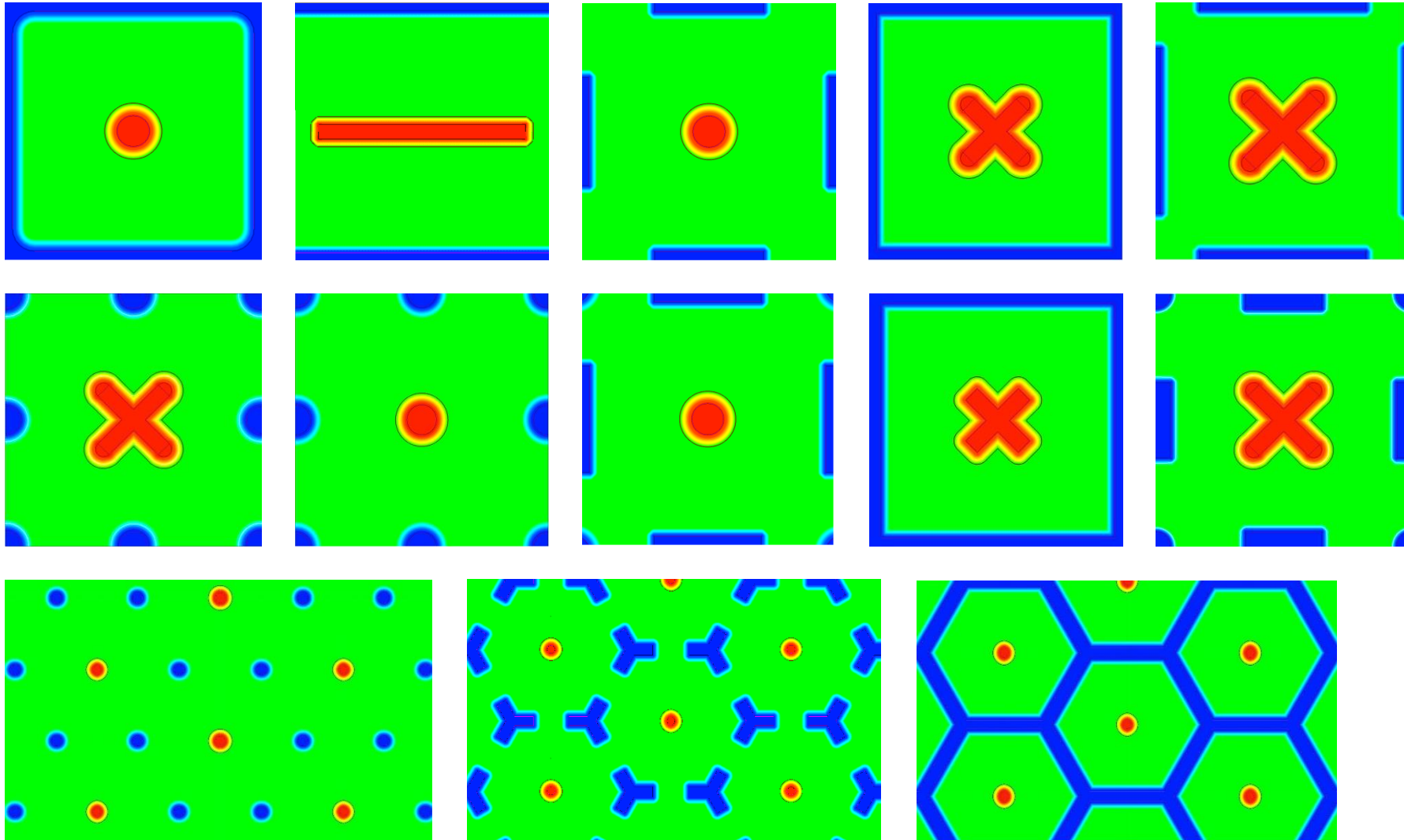
Second Title

Designed geometries

- More than **15** different geometric configurations were explored.
- Each single geometry was also designed in till 30 different ways, which means that overall there were explored **more than 200 different** pixel geometries, which are organised in two main configurations
 - **Hexagonal pixel** geometry with 50 μm in diameter (4 models)
 - **Square pixel** geometry with 50 μm x 50 μm dimension (more than 11 models)
- All designs have in common the following characteristics:
 - Doping concentrations:
 - P++/N++ doping concentration
 - P- substrate doping concentration
 - Trench dimension:
 - 6 μm and 3 μm width
 - Column dimension
 - 6 μm and 3 μm diameter
 - 2D models represent only **25%** of the entire pixel section
 - P-electrode potential is set @ -100 V

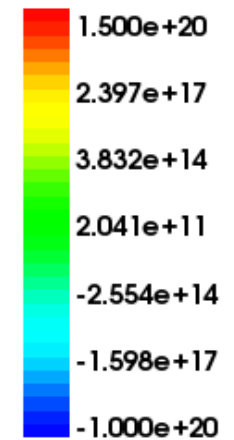


Some examples (doping maps)



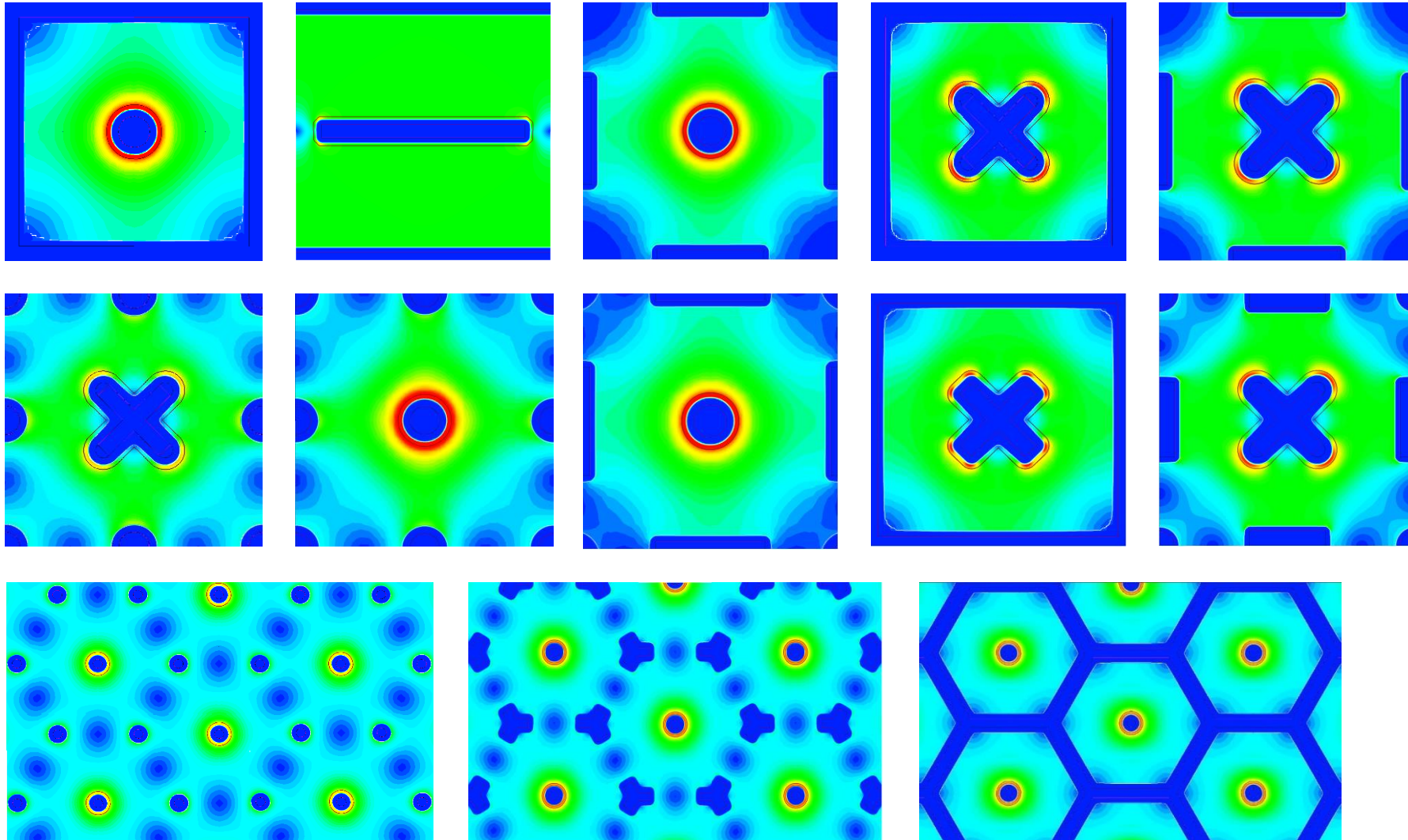
Square pixel geometries

DopingConcentration (cm⁻³)



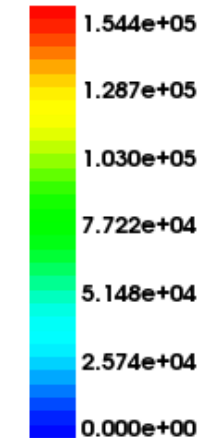
Hexagonal pixel geometries

Some examples (electric field maps)



Square pixel geometries

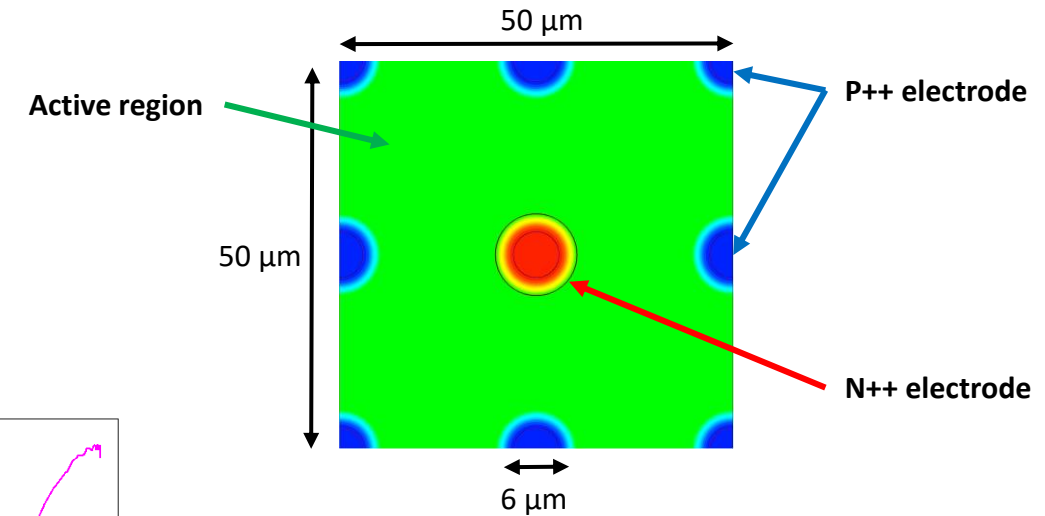
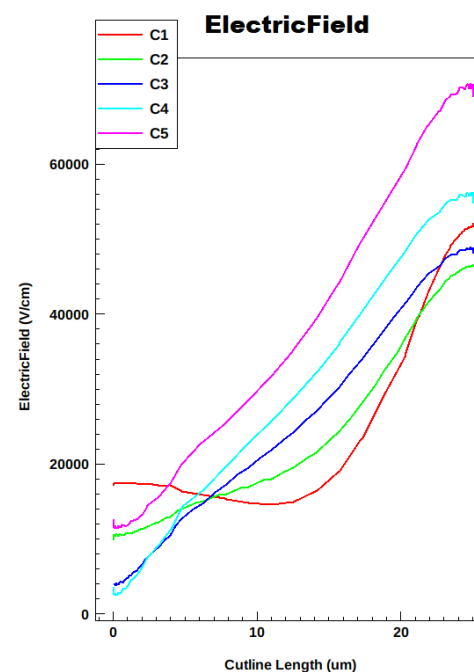
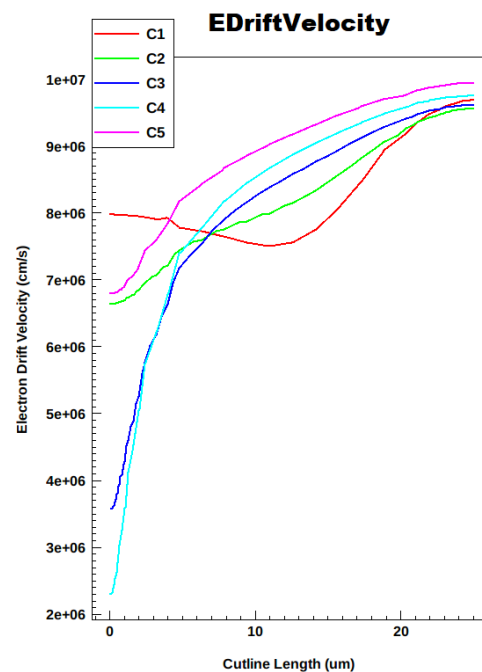
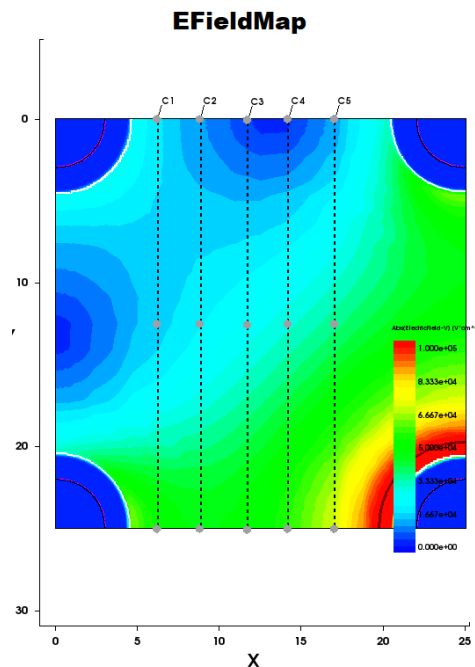
$Abs(ElectricField-V)$ ($V \cdot cm^{-1}$)



Hexagonal pixel geometries

Rejected solutions, some examples (1)

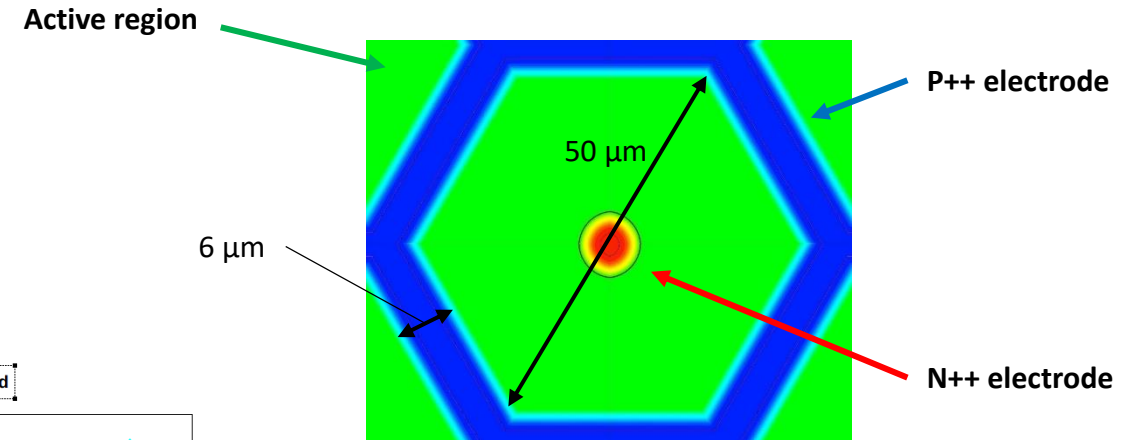
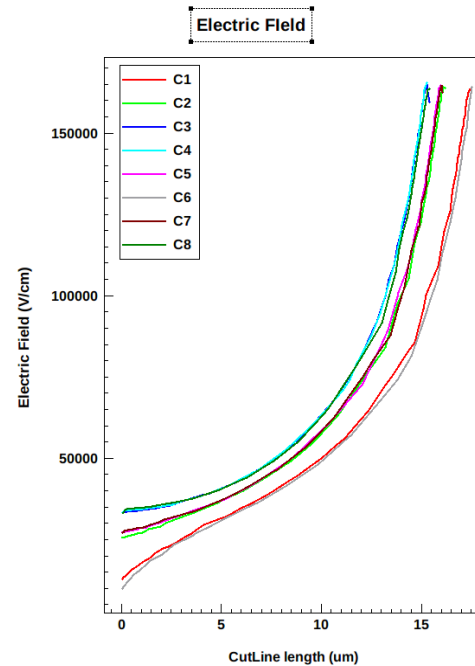
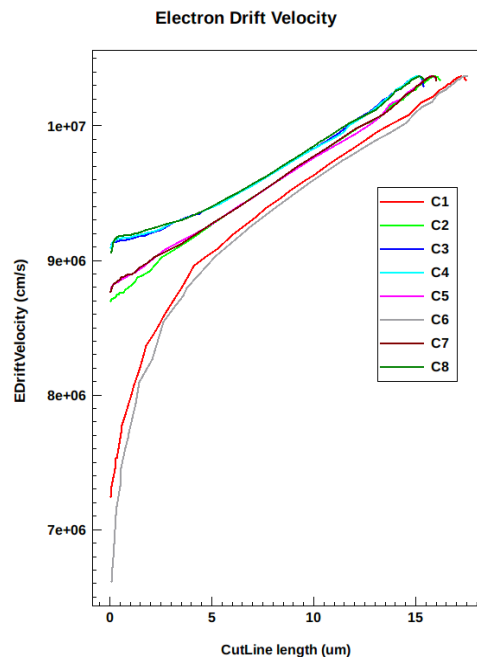
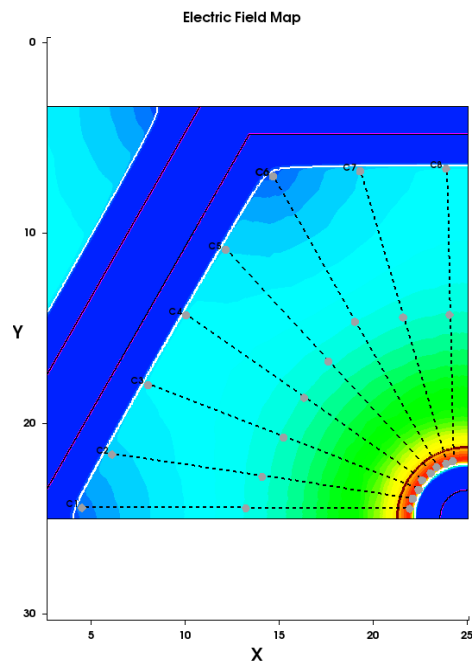
- Square pixel with columnar electrodes
 - Electric field changes too much over all the pixel area.
 - 15 kV/cm over the low field area
 - Over 100 kV/cm near the collector electrode



- Electric Field:
 - Electric field changes too much over all the pixel area.
- Drift Velocity:
 - Decreases too much inside the low field areas

Rejected solutions, some examples (2)

- Hexagonal pixel with continuous trench frame electrode
 - Electric field changes too much over all the pixel area.
 - 15 kV/cm over the low field area
 - Over 100 kV/cm near the collector electrode

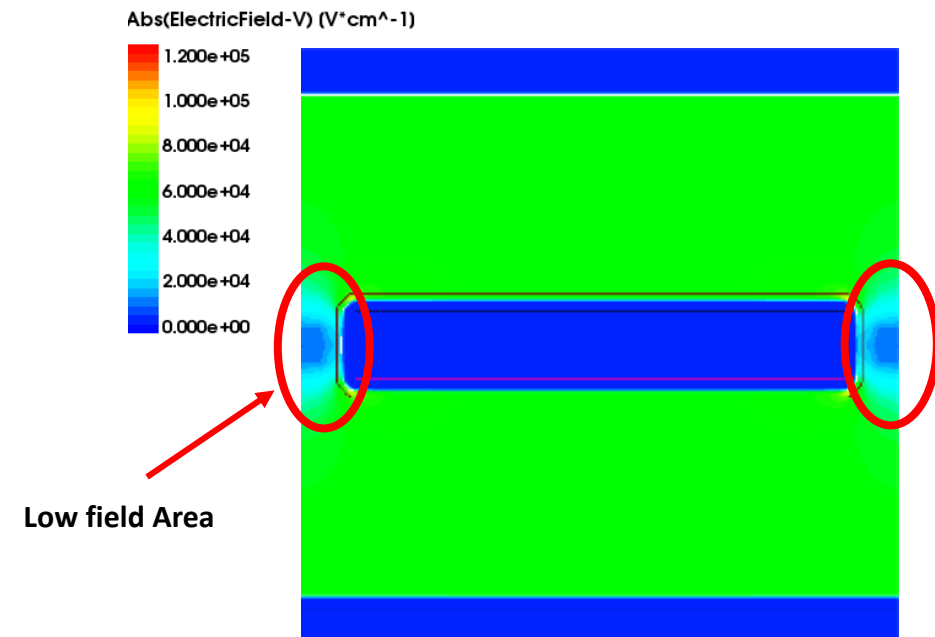
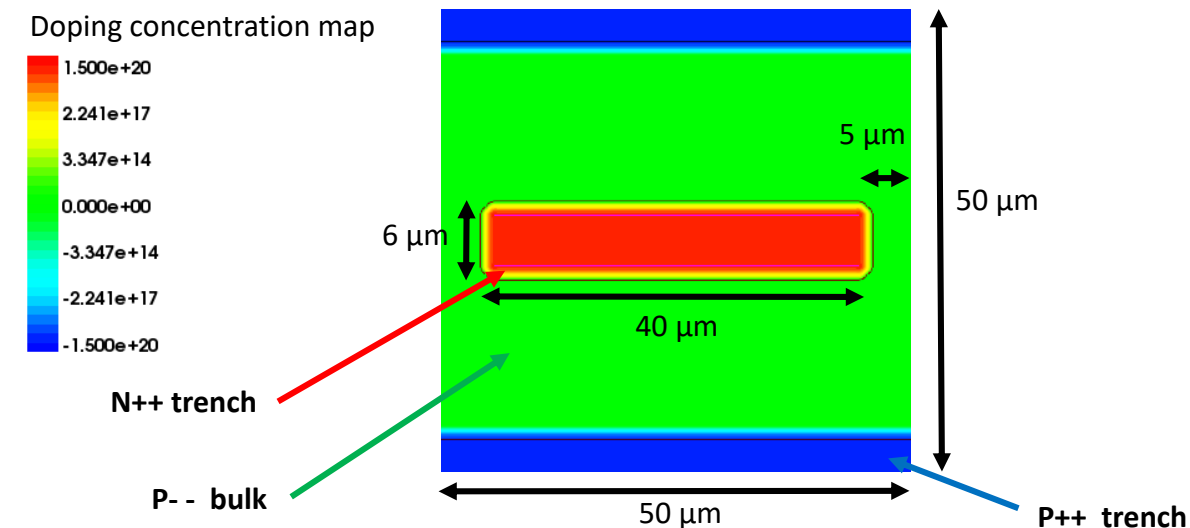


- Electric Field:
 - Electric field changes too much over all the pixel area.
- Drift Velocity:
 - Decreases too much inside the low field areas, like previous geometry.

Chosen solution: Par trench geometry

- Parallel trench geometry:
 - 50 μm x 50 μm pixel
 - 3 parallel trenches
 - Two external with same doping (P++) for bias
 - One 10 μm shorter central trench for signal acquisition (N++ doped trench)
 - 32 different designs were explored, changing:
 - Pixel dimension: (50 μm x 50 μm) and (100 μm x 100 μm)
 - Trench width (3 μm and 6 μm)
 - Central Trench Length (from 35 μm to 45 μm)

- Electric field:
 - Is the most uniform of all explored geometries
 - Low field areas cover ca. 1.5 % of the entire area (34 μm^2)
 - Areas between two N-electrodes
 - Charge collection remains fast due to the extremely short distance to the electrodes



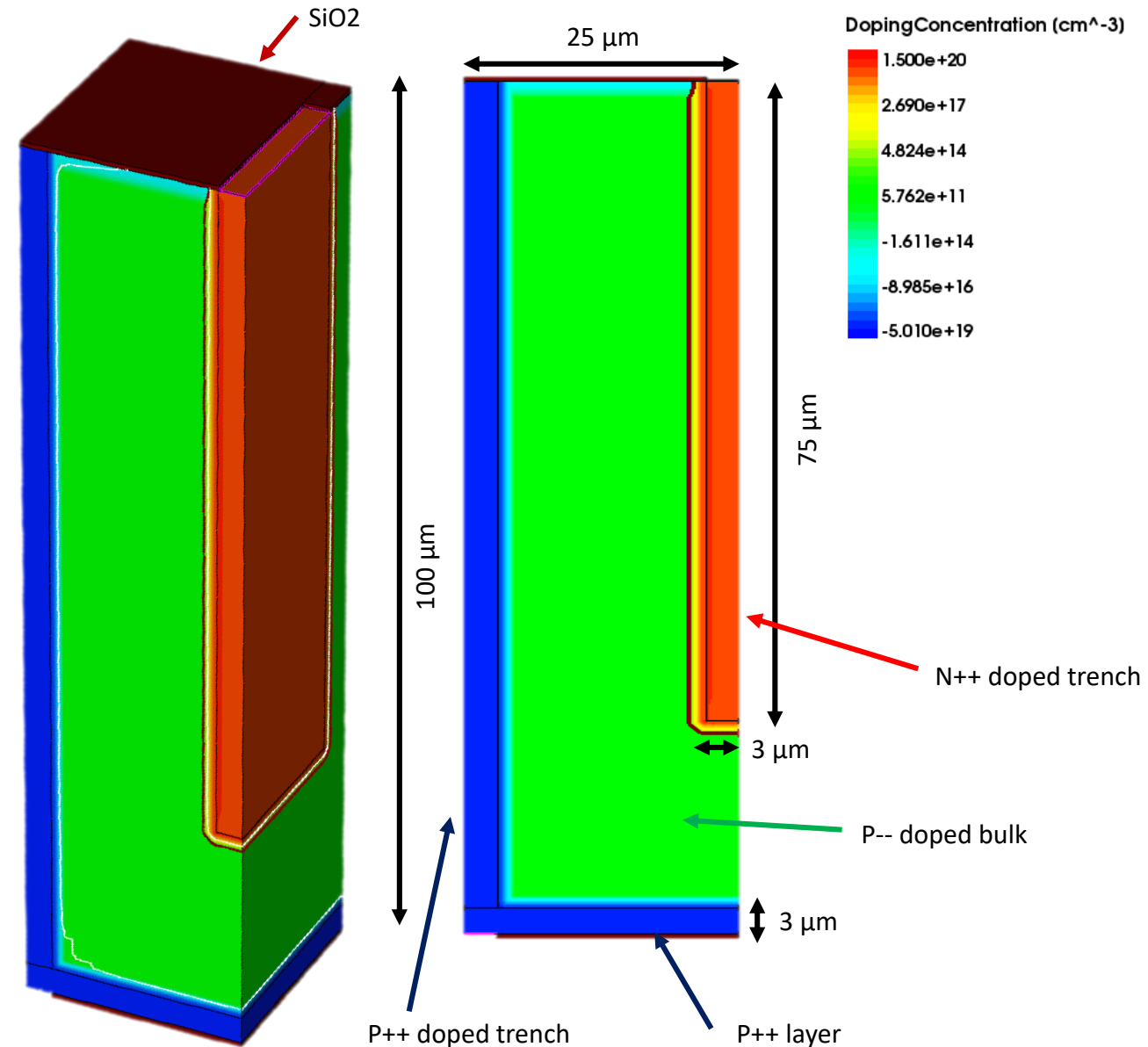
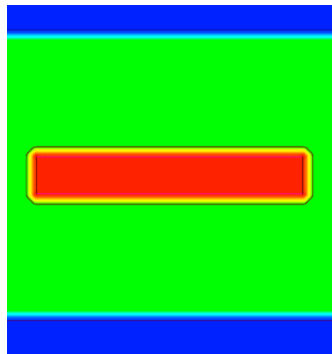
3D model design

Second Title

Par trench 3D model (1)

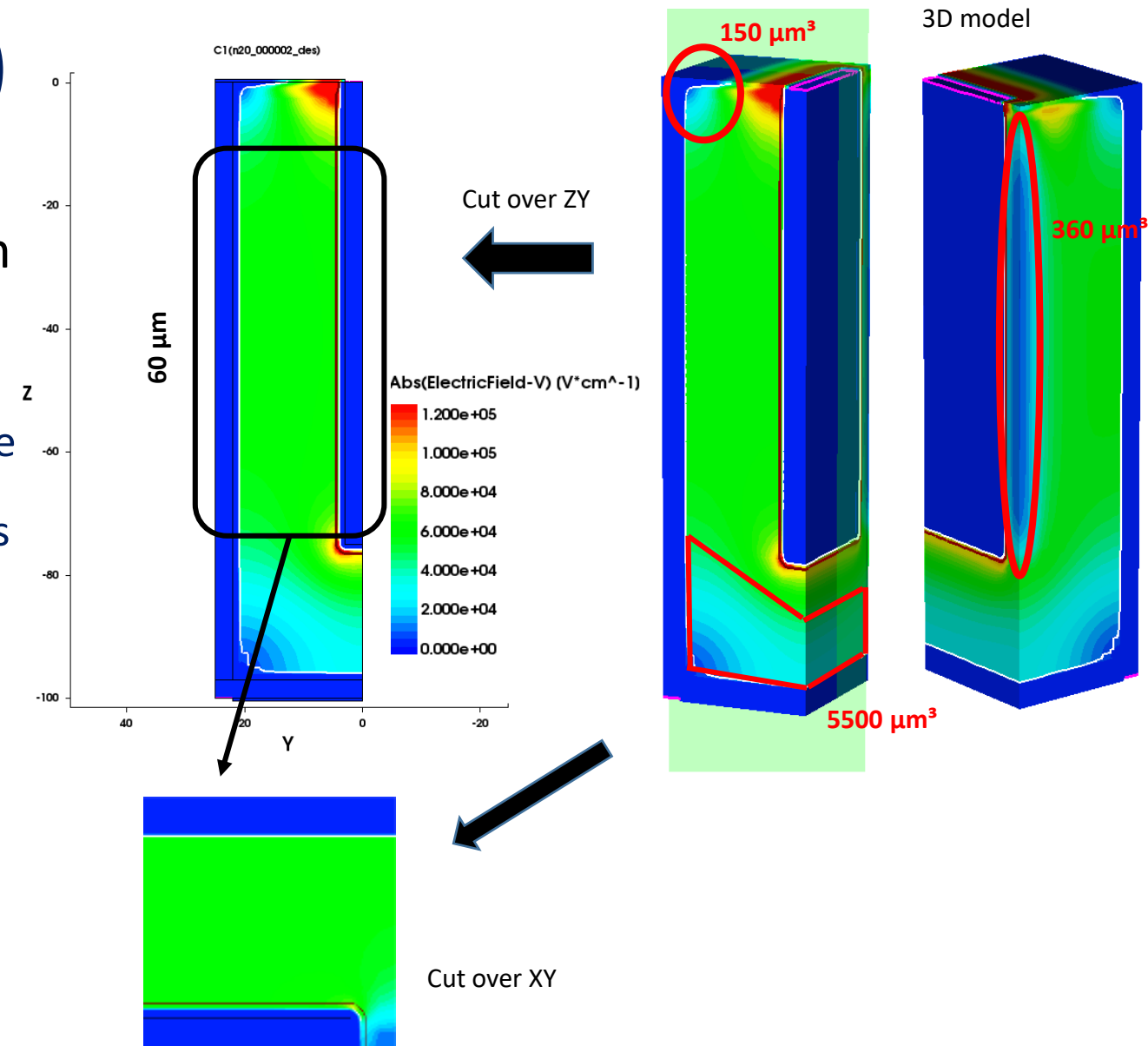
- 3D model of the chosen solution was designed in order to understand the behaviour of the electric field and charge velocity through the entire detector volume.
 - Model represents 25% of the entire pixel

2D model along XY



Par trench 3D model (2)

- 3D simulation shows that there is a second larger low field area at the bottom of the pixel volume
 - Possibility that this area can reduce charge collection.
 - Low field regions covers ca. 10 % of the entire sensitive volume
 - Solutions must be found in order to reduce its area.



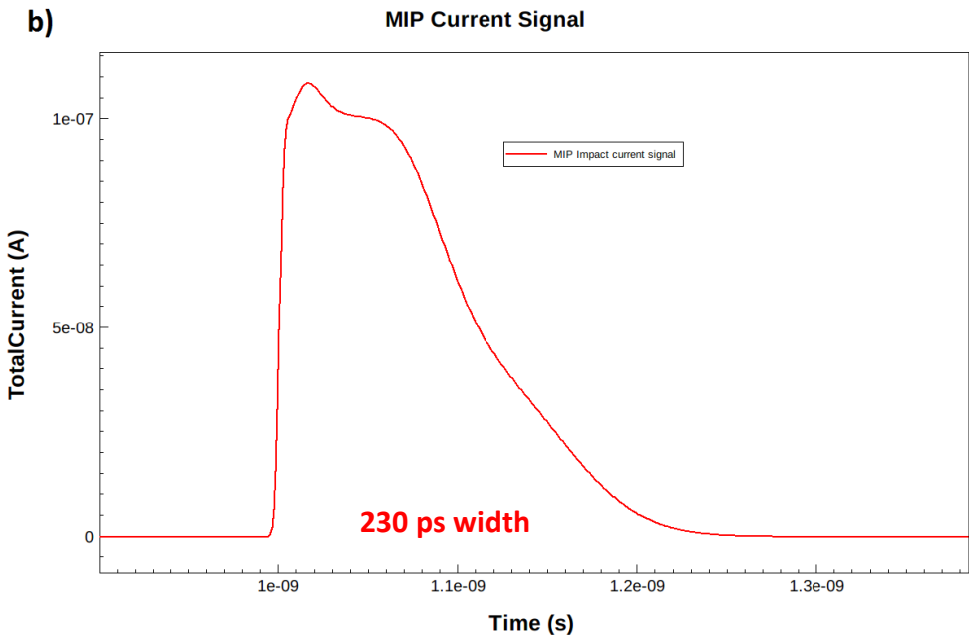
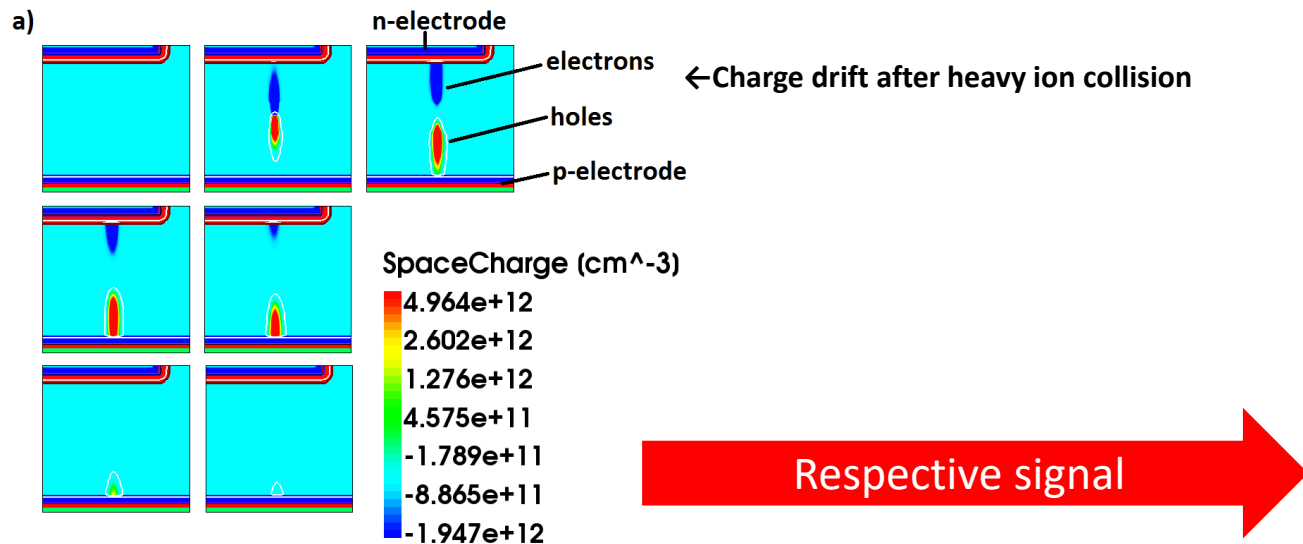
Current status

Signal generation

Signal generation on 2D models (1)

- TCAD is not specifically developed for particle detector design
- It is possible to emulate the passage of a high energy proton, by injecting charge in a specific location (or track) inside the detector during a transient simulation
 - Setting a LET of 80 electron/ μm corresponds to an High energy proton passage

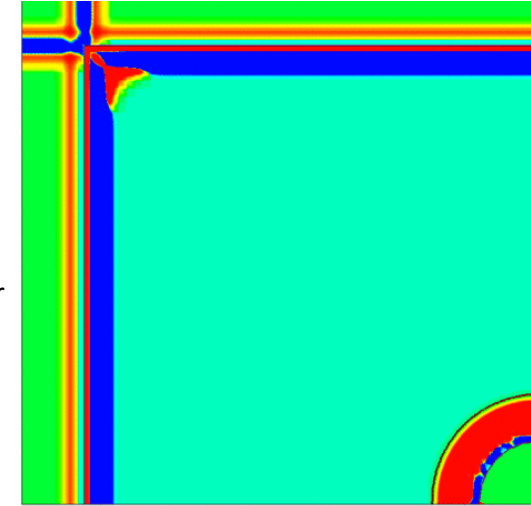
- Problems:
 - Impossible to observe the tracks of single charges
 - LET is too deterministic



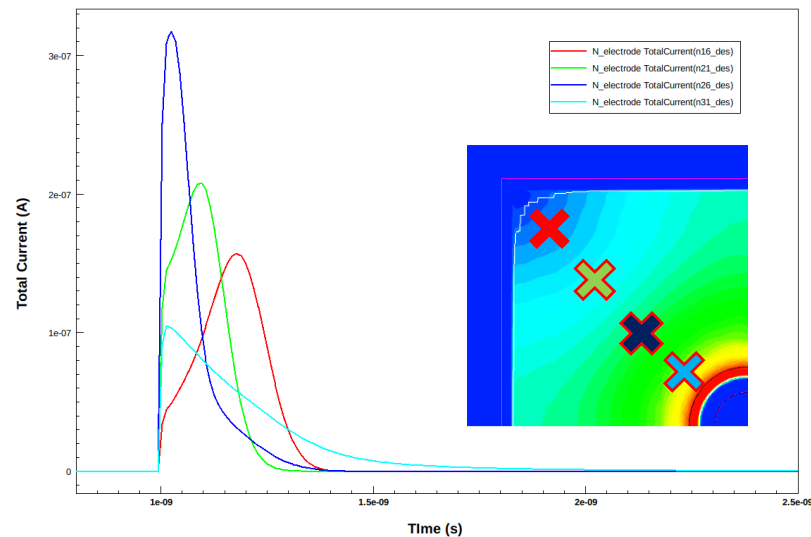
Signal generation on 2D models (2)

- Output signal shape was at first explored on 4 different 2D models
 - Dividing the area of the 2D model into approx. 25 (16) cells
 - During a transient simulation, 80 e-/h pairs were injected inside only one of the 25 cells

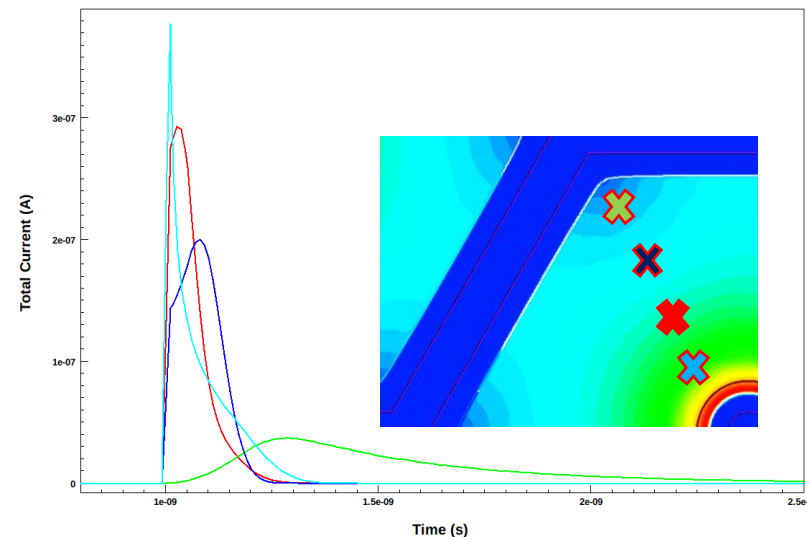
Charge density map representing 15 MIP crossing the pixel and the drift of the e-h pair to their respective electrodes →



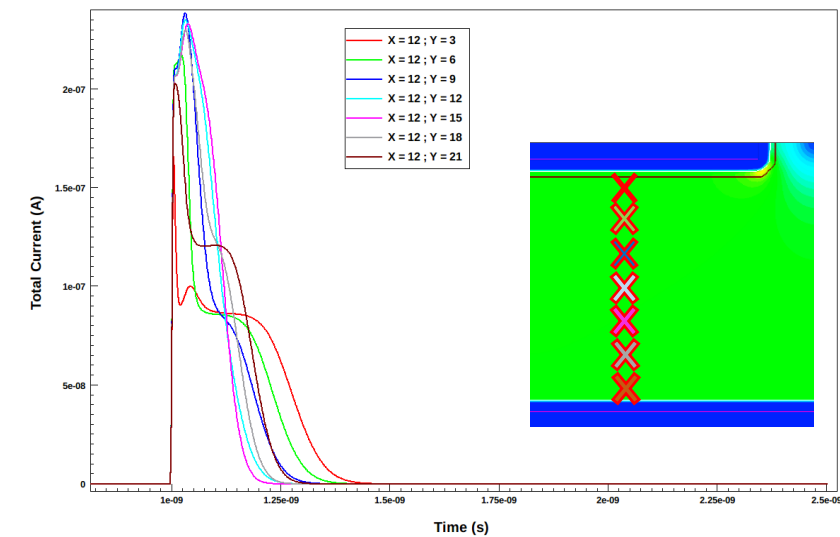
Square pixel with central column



“Closed” hexagon with central column

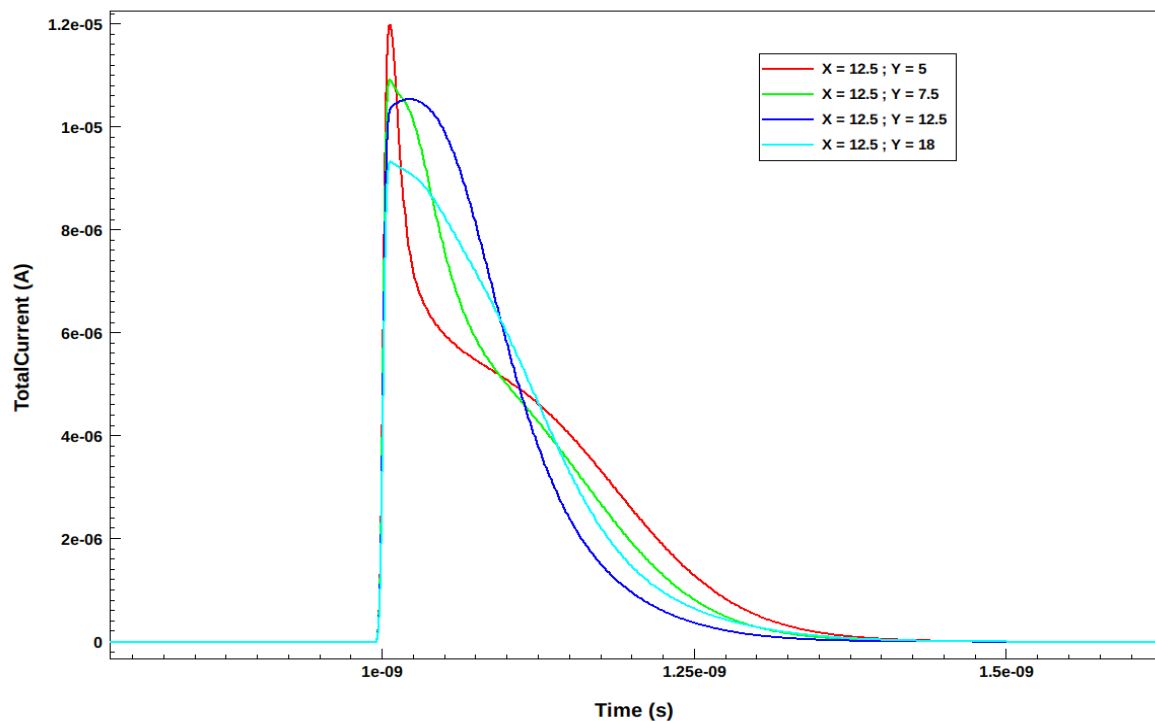


Parallel trench pixel

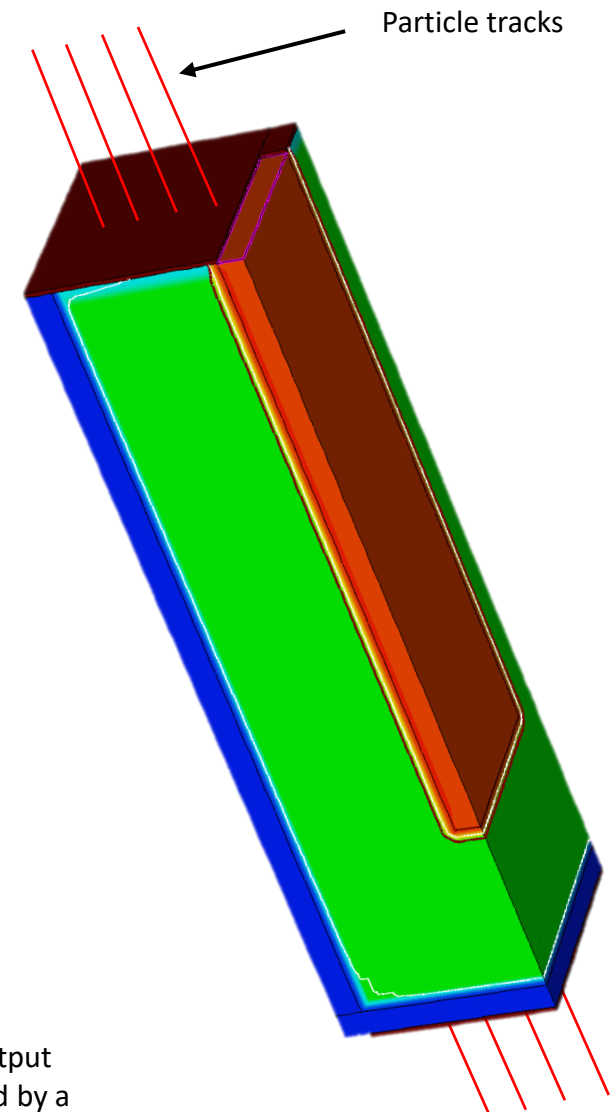


Signal generation on 3D models

- Same approach was used for the 3D model
 - Signals are more similar to each other
 - Signal width is still the same (less than 300 ps)
 - Important: There is no evidence that the low field areas are reducing charge collection.

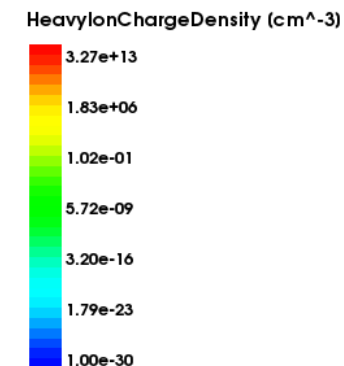
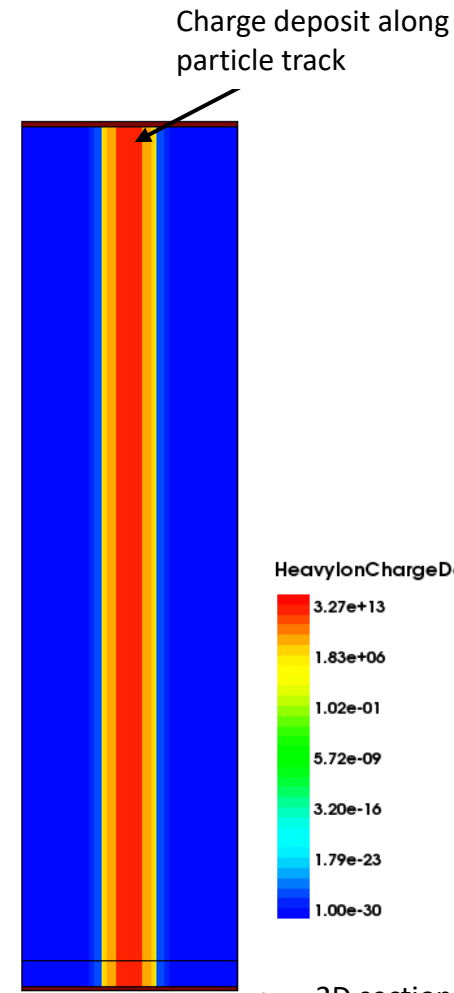
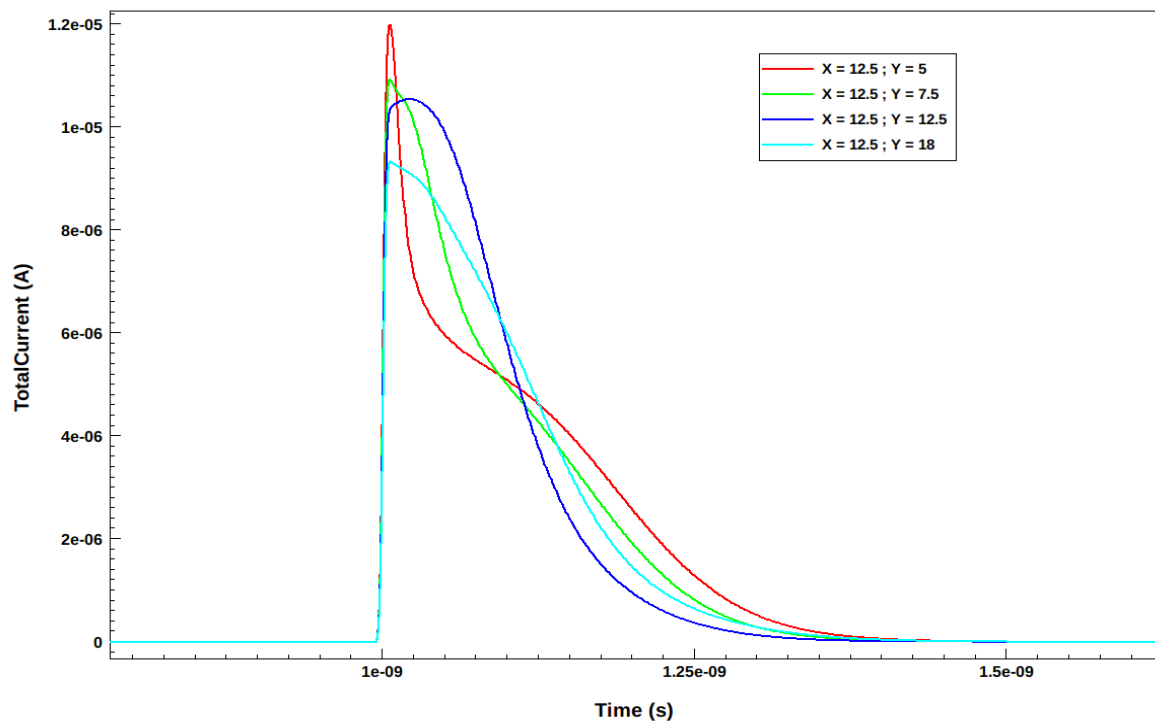


Plots watching the total current output signal of the detector when crossed by a MIP

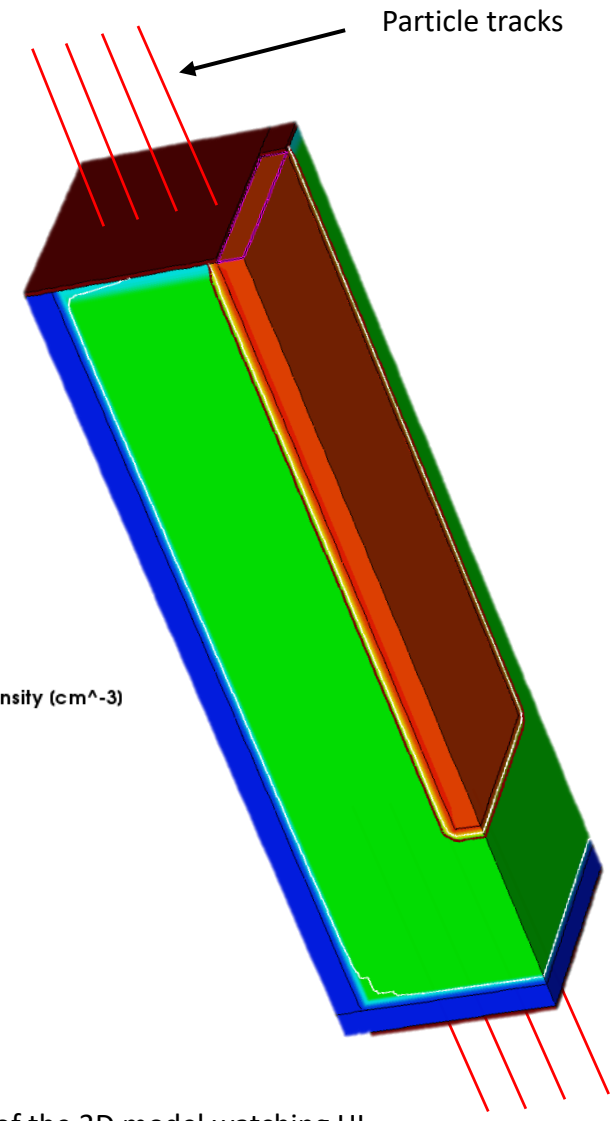


Signal generation on 3D models

- Same approach was used for the 3D model
 - Energy deposit is still too uniform over all the track!
 - Need a more realistic model for the charge deposit along the particle track!

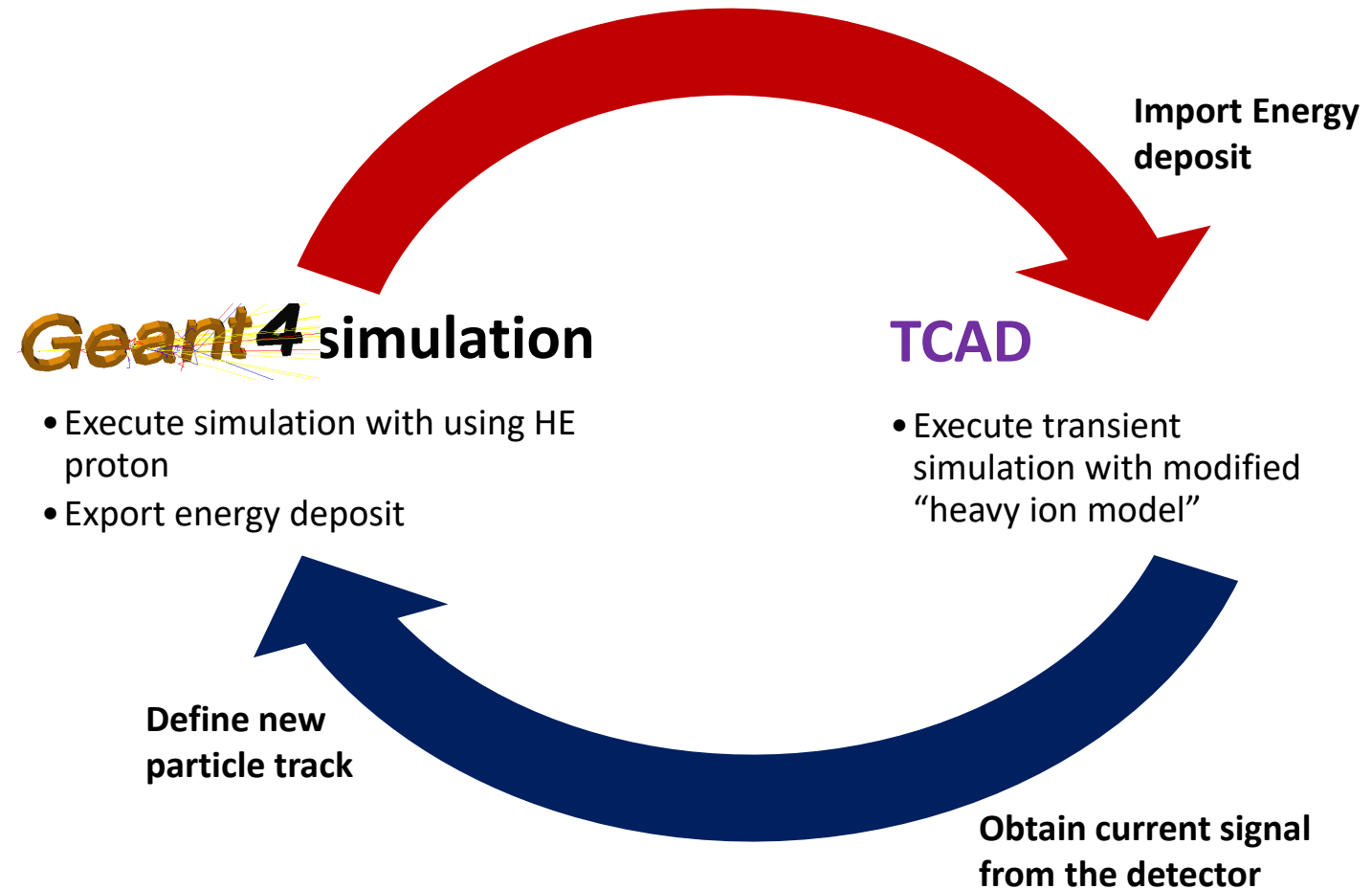


2D section of the 3D model watching HI charge density deposit



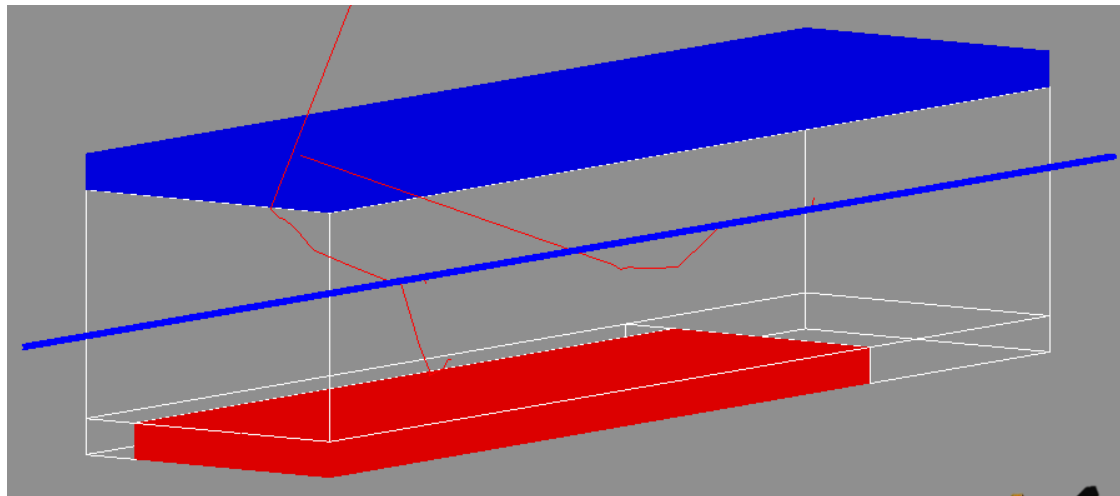
Signal generation using extra tools (1)

- TCAD and Geant4 approach:
 - Reproducing a same scale model of the detector in Geant4
 - Simulating the passage of an high energy proton through the pixel
 - Export the energy deposit of the particle
 - Using the energy deposit of G4 to customise the heavy ion model of TCAD on a specific “.par” file
 - Start Sdevice simulation with modified HIM



Signal generation using extra tools (2)

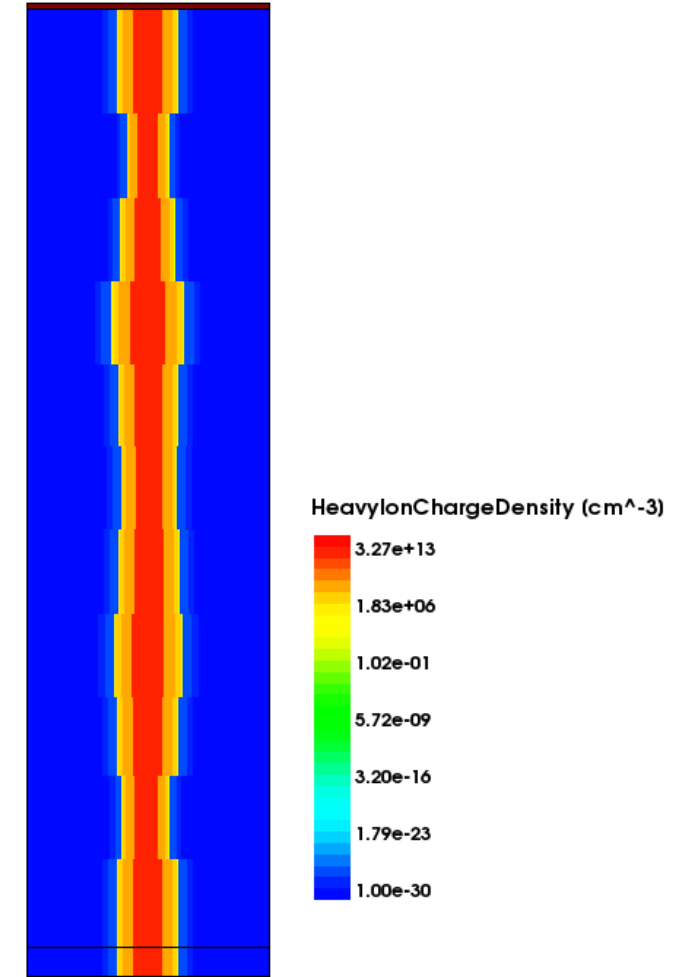
- What is already done
 - 3D model in G4 reproduced
 - Physics is defined
 - Main physics used is the G4 microelectronics package.
 - First test simulations done
- Current work in progress:
 - Defining the sensitive volume
 - Find a way to export the energy deposit in a .root file



Geant4

What I'm expecting to see after importing the energy deposit in TCAD →

← Geant4 Simulation watching the passage of an 5 GeV proton (blue track) through the pixel. Red tracks represents negative charged fast particles generated by the passage (already done).



Conclusions

Second Title

Conclusions

- Started to explore a geometry solution for a 3D silicon detector
 - Starting from 2D models
 - Select the geometry with the best parameters
 - 3D model of the solution was designed and tested too.
- Pixel output signal was simulated
 - Starting only using TCAD
 - Improving simulation using Geant4 to define the energy deposit

Backup

Second Title

1) Heavy Ion Model

Short Description

Heavy Ion model

- Heavy Ion Mmodel

```

HeavyIon(
  Direction = (0, 0, 1)
  Location  = (12, 12, 0)
  Time      = 1e-9
  Length    = 10
  LET_f     = 80
  Gaussian
)
    
```

Particle path direction (x,y) → Direction

Start point (x,y) → Location

Start time → Time

Path length → Length

Charge deposition width → LET_f

Charge deposition/μm → LET_f

Charge distribution Shape along axis → Gaussian

↑ Sentaurus Device Heavy Ion interaction Code

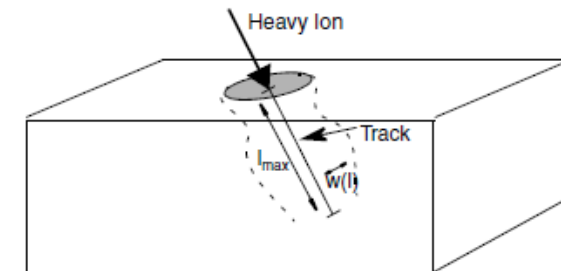


Figure 53 A heavy ion penetrating a semiconductor; its track is defined by a length and the transverse spatial influence is assumed to be symmetric about the track axis

Generation rate: $G(l, w, t) = G_{LET}(l)R(w, l)T(t)$

$$G_{LET}(l) = a_1 + a_2l + a_3e^{a_4l} + k' [c_1(c_2 + c_3l)^{c_4} + LET_f(l)] = LET_f(l)$$

Normal HIM

Table 112 Coefficients for carrier generation by heavy ion (HeavyIon parameter set)

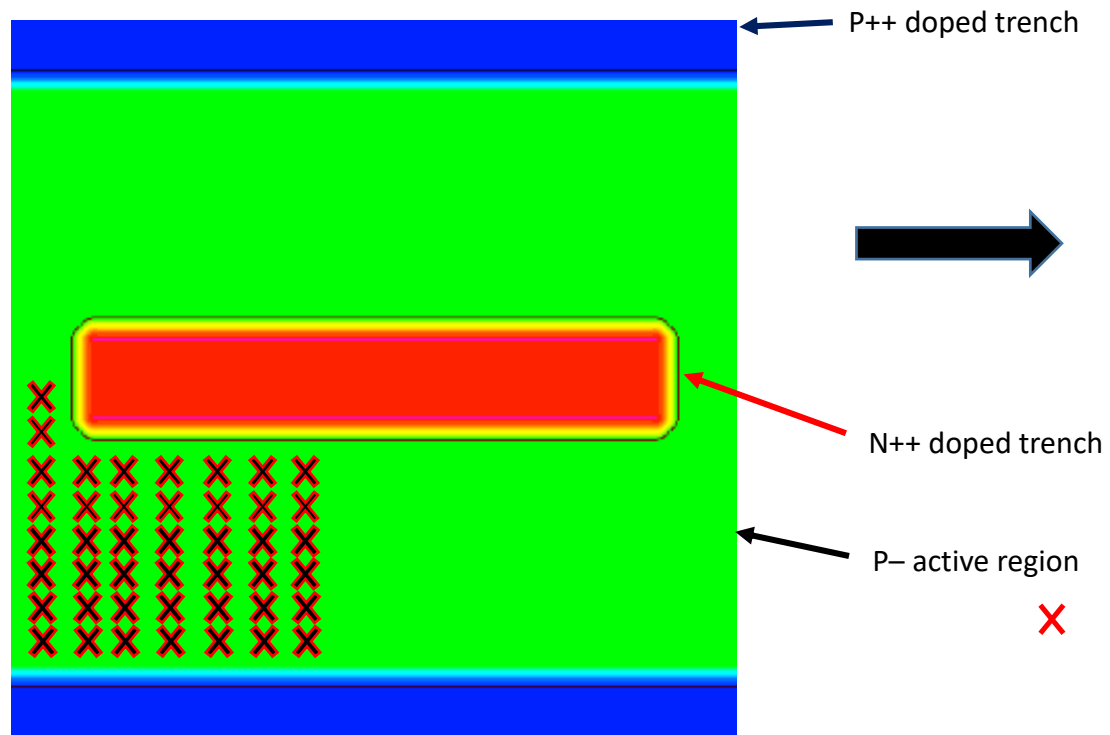
	s_{hi}	a_1	a_2	a_3	a_4	k	c_1	c_2	c_3	c_4
Keyword	s_hi	a_1	a_2	a_3	a_4	k_hi	c_1	c_2	c_3	c_4
Default value	2e-12	0	0	0	0	1	0	1	0	1
Default unit	s	pairs/cm ³	pairs/cm ³ /cm	pairs/cm ³	cm ⁻¹	1	pairs/cm ³	1	cm ⁻¹	1
Unit if PicoCoulomb is chosen	s	pairs/cm ³	pairs/cm ³ /μm	pairs/cm ³	μm ⁻¹	1	pC/μm	1	μm ⁻¹	1

2) 2D Signal simulation

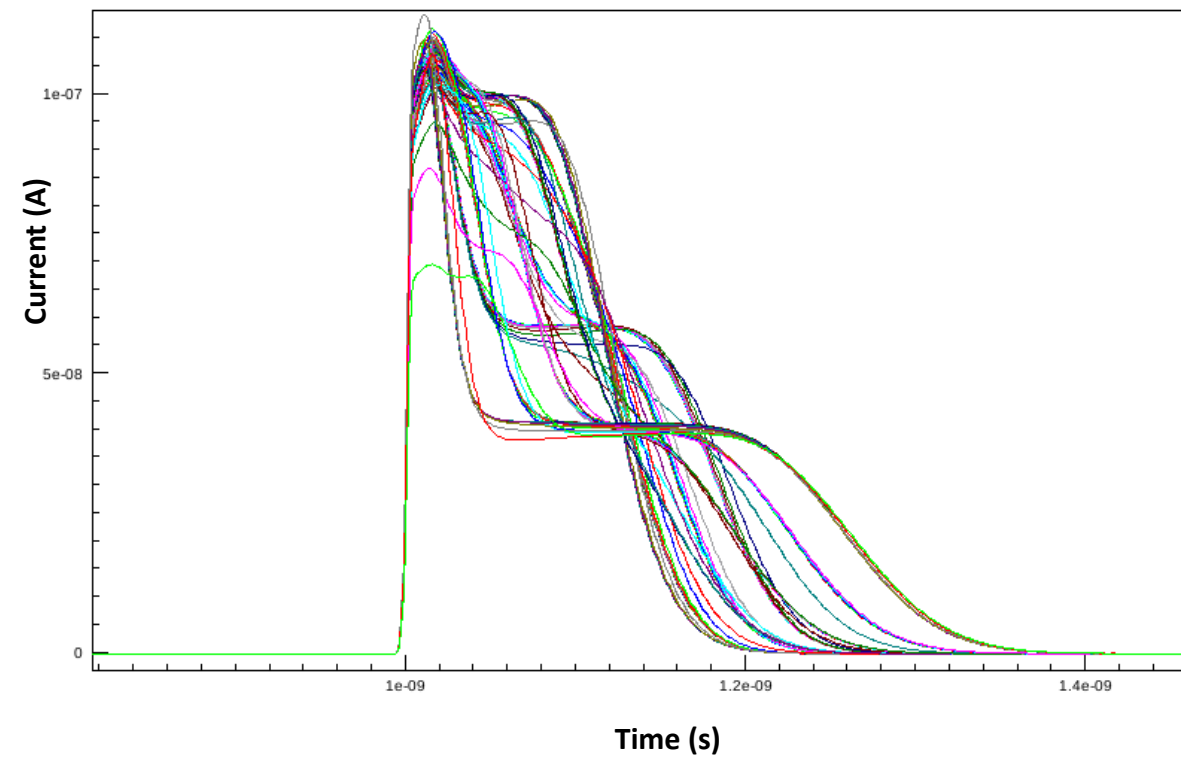
All generated curves for the par trench design

Signal generation

- Charge injection points and respective output current signals

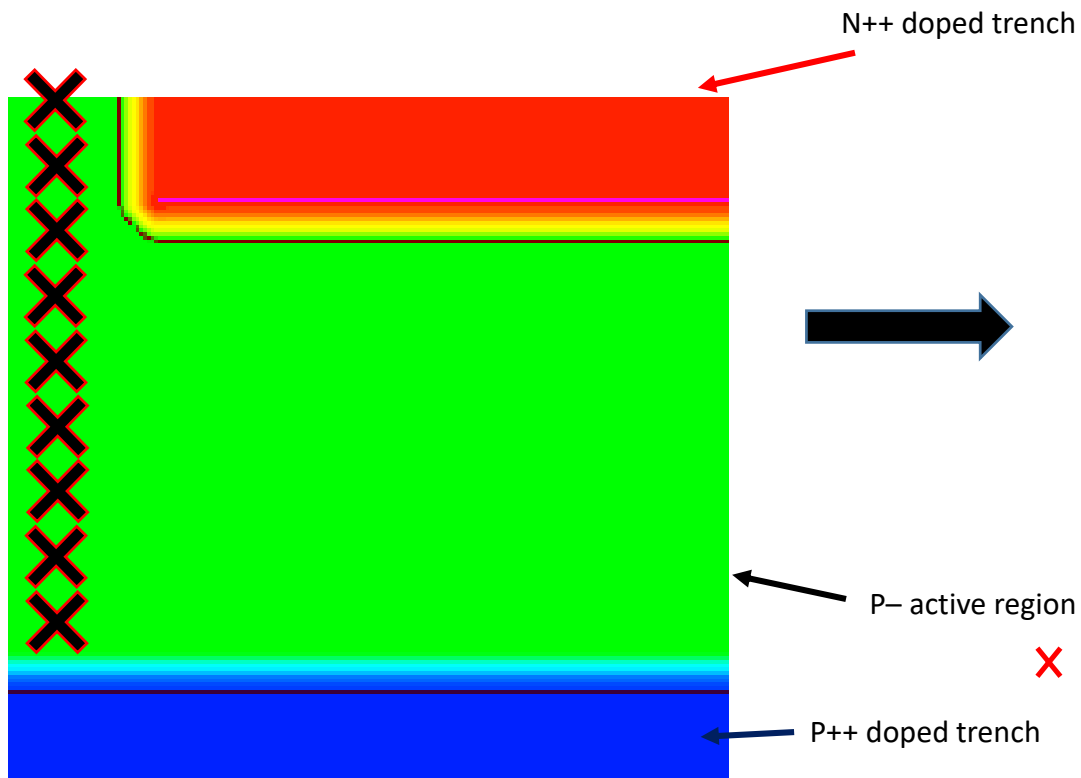


Doping concentration map

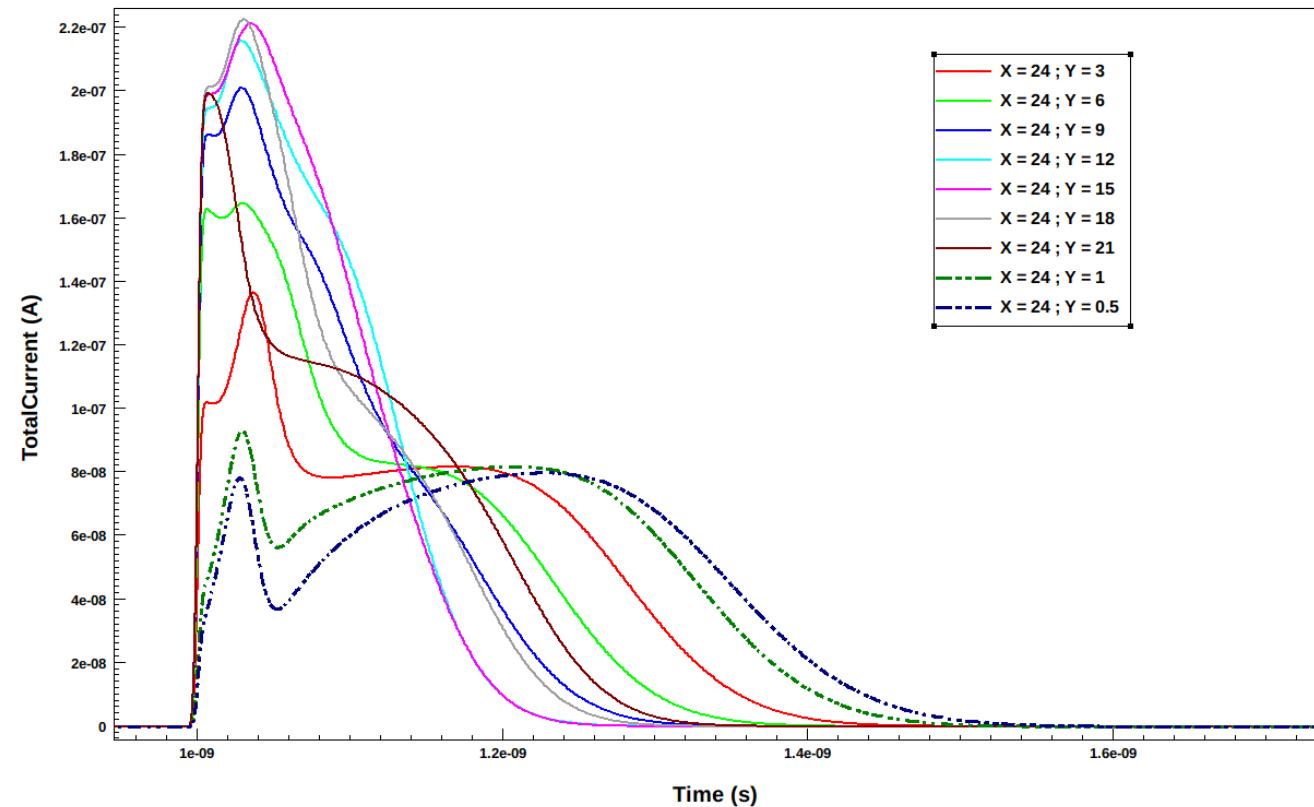


Signal generation

- Charge injection points and respective output current signals:
 - Signals produced along the low field region



Doping concentration map



Signal generation

- Charge injection points and respective output current signals
 - Centre of the 2D model (left) vs low field region (right)

